

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
Kiyofumi SAKAGUCHI, et al.	)	Examiner: George R. Fourson, III
	)	
Appln. No.: 10/085,046	)	Group Art Unit: 2823
	)	
Filed: March 1, 2002	)	Confirmation No.: 7805
	)	
For: PROCESS FOR PRODUCTION OF	)	
SEMICONDUCTOR SUBSTRATE	)	November 7, 2006

**Mail Stop Amendment**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

FIFTH INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents, other than U.S. patent documents, are enclosed.

REMARKS

An English-language Abstract for JP-A 60-196955 was obtained from a commercial database and is also enclosed.

### FORMAL MATTERS

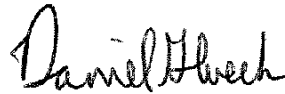
No fee is believed due; however, any fee required in connection with this paper should be charged to Deposit Account No. 06-1205.

### CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



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FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)  Dated Submitted to USPTO: November 7, 2006				ATTY DOCKET NO. <b>03500.010530.5</b>		APPLICATION NO. <b>10/085,046</b>	
				APPLICANT <b>Kiyofumi SAKAGUCHI, et al.</b>			
				FILING DATE <b>March 1, 2002</b>		GROUP <b>2823</b>	
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		5,175,610	12/29/1992	Kobayashi	257	676	
		4,670,763	06/02/1987	Ovshinsky, et al.	357	4	
		4,555,586	11/26/1985	Guha, et al.	136	259	
		4,426,657	01/17/1984	Abiru, et al.	357	29	
		4,064,521	12/20/1977	Carlson	357	2	
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
		60-196955	10/05/1985	Japan			Abstract
		0 469 630 A2	02/05/1992	Europe			
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
		T. Yasumatsu, et al., "Ultrathin Si Films Grown Epitaxially on Porous Silicon", Applied Surface Science, Vols. 48 & 49, pp. 414-418 (1991)					
		Handbook of Thin Film Technology, 5-17 to 5-25 (Eds., L. I. Maissel and R. Glang 1970)					
		Robert F. Pierret, Semiconductor Device Fundamentals, pp. 347-368					
EXAMINER				DATE CONSIDERED			

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet 1 of 2

FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)  Date Submitted to USPTO: November 7, 2006			ATTY DOCKET NO. <b>03500.010530.5</b>		APPLICATION NO. <b>10/085,046</b>		
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U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)	
	<b>S.M. Sze, Physics of Semiconductor Devices, pp. 63-128, 847-849, 2<sup>nd</sup> Edition (1981)</b>
	<b>W. Kern &amp; V. Ban, <u>Thin Film Processes</u>, Chemical Vapor Deposition of Inorganic Thin Films, pp. 257-331 (1978)</b>
	<b>W. Luft &amp; Y. Tsuo, <u>Hydrogenated Amorphous Silicon Alloy Deposition Processes</u>, pp. 125-144 (1993)</b>
	<b>R. Pierret, Modular Series on Solid State Devices, Vol. 4, pp. 59-80 (1983)</b>

EXAMINER	DATE CONSIDERED
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